EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	15	(@ad<="20030331") and (216/13.ccls.) and piezoelectric and resonator and (protecti\$4 or stop or insulat\$3 or selectiv\$4 or encapsulat\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 16:32
S1		(@ad<="20030331") and (piezoelectric with resonator)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR ·	ON	2007/03/14 13:33
S2	111	(@ad<="20030331") and (piezoelectric with resonator) and (protect\$4 adj layer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/07/11 16:41
S3	29	(@ad<="20030331") and (piezoelectric with resonator) and ((protect\$4 adj layer) with etch\$4)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/09 14:40
S4	113	(@ad<="20030331") and (piezoelectric with resonator) and (protect\$4 adj layer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:38
S5	1	("6933807").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF _.	2007/03/13 12:45
S6	. 42	(@ad<="20030331") and (piezoelectric with resonator) and ((etch adj1 stop) or etchstop)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/14 14:09
\$7	2	("20040191947").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/03/14 14:09
S8	4	(@ad<="20030331") and (piezoelectric with resonator) and (encapsulat\$4 adj layer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/14 16:56
S9	17	(@ad<="20030331") and (piezoelectric with resonator) and (isolat\$4 adj layer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 09:36

EAST Search History

S10	2023	(@ad<="20030331") and (29/25.35.cds.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 09:36
S11	1536`	(@ad<="20030331") and (29/25.35.ccls.) and piezoelectric	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 09:36
S12	369	(@ad<="20030331") and (29/25.35.ccls.) and piezoelectric and resonator	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 09:37
S13	250	(@ad<="20030331") and (29/25.35.ccls.) and piezoelectric and resonator and (protecti\$4 or stop or insulat\$3 or selectiv\$4 or encapsulat\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 16:32
S14		(("5714917") or ("6617249") or ("6812473")).PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/03/15 09:53
S15	3	(("5714917") or ("6617249") or ("6812473")).PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	OFF	2007/03/15 10:10
S16 ·	1	("20040200050").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	OFF	2007/03/15 10:11
S17 .	1818	(@ad<="20030331") and (piezo\$ same (protect\$3 with (cover layer)))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:40
S18	601	(@ad<="20030331") and (piezo\$ same (protect\$3 with (cover layer))) and (oxide or "sio.sub.2")	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:41
S19	1397	(@ad<="20030331") and (piezo\$ same (protect\$3 or ("cover layer"))) and (oxide or "sio.sub.2")	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:42

EAST Search History

S20 <u>.</u>	150	(@ad<="20030331") and ((piezo\$ same (protect\$3 or ("cover layer"))) with (oxide or "sio.sub.2"))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:45
S21	8	(@ad<="20030331") and ((piezo\$ same (protect\$3 or ("cover layer"))) with (oxide or "sio.sub.2")) and (310/36\$1.ccls.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:52
S22	10	(@ad<="20030331") and (piezo\$ same (encapsulat\$3 or coat\$3)) and (310/349.ccls.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:59
S23	110	(@ad<="20030331") and (piezo\$ same (encapsulat\$3 or coat\$3)) and (310/340.ccls.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:02
S24	3	(@ad<="20030331") and ((piezo\$ same (encapsulat\$3 or coat\$3)) with etch\$3) and (310/340.ccls.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:03

3/15/2007 4:58:53 PM C:\Documents and Settings\mdahimene\My Documents\EAST\Workspaces\Apl 10811812.wsp

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PALM INTRANET

Time: 10:23:30

Inventor Name Search Result

Your Search was:

Last Name = KOMURO

First Name = EIJU

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09028116	<u>5943156</u>	150	02/23/1998	POLARIZING PLATE AND METHOD OF MANUFACTURING POLARIZING PLATE	KOMURO, EIJU
09207659	6251297	150	12/09/1998	METHOD OF MANUFACTURING POLARIZING PLATE	KOMURO, EIJU
10031239	7046103	150	04/02/2002	ELECTRIC FILTER COMPRISING A PLURALITY OF THIN FILM BULK ACOUSTIC RESONATORS	KOMURO, EIJU
10031240	6774746	150	04/02/2002	THIN FILM BULK ACOUSTIC RESONATOR FILTERS WITH A PIEZOELECTRIC LAYER OF LEAD SCANDIUM TANTALUM OXIDE	KOMURO, EIJU
10069754	Not Issued	161	02/28/2002	Method For Hermetically Packaging Bulk Acoustic Resonator Device	KOMURO, EIJU
10260265	6778038	150	10/01/2002	PIEZOELECTRIC RESONANT FILTER, DUPLEXER, AND METHOD OF MANUFACTURING SAME	KOMURO, EIJU
10380985	7187254	150	03/20/2003	FILM BULK ACOUSTIC RESONATOR FILTERS WITH A COPLANAR WAVEGUIDE	KOMURO, EIJU
10486719	7078984	150	02/13/2004	DUPLEXER AND METHOD OF MANUFACTURING SAME	KOMURO, EIJU
10670234	6977563	150	09/26/2003	THIN-FILM PIEZOELECTRIC RESONATOR AND METHOD FOR FABRICATING THE SAME	KOMURO, EIJU
10718799	7199504	150	11/24/2003	FILM BULK ACOUSTIC	KOMURO, EIJU

				RESONATOR FILTER	
10731157	6989723	150	I I	PIEZOELECTRIC RESONANT FILTER AND DUPLEXER	KOMURO, EIJU
10806378	6954117	150	03/23/2004	ELECTRONIC COMPONENT INCLUDING PIEZO-ELECTRIC RESONATOR MOUNTED BY FACE-DOWN BONDING WITH A REQUIRED DIE SHEAR STRENGTH	KOMURO, EIJU
10806469	Not Issued	161	03/23/2004	Compact electronic component including piezo-electric resonator mounted by face-down bonding with improved reliability	KOMURO, EIJU
10811812	Not Issued	71	03/30/2004	Method of manufacturing a piezoelectric thin film resonator, manufacturing apparatus for a piezoelectric thin film resonator, piezoelectric thin film resonator, and electronic component	KOMURO, EIJU
10814120	7109637	150	04/01/2004	THIN-FILM BULK ACOUSTIC OSCILLATOR AND METHOD OF MANUFACTURING SAME	KOMURO, EIJU
10819134	7124485	150	04/07/2004	METHOD OF MANUFACTURING A PIEZOELECTRIC THIN FILM RESONATOR, MANUFACTURING APPARATUS FOR A PIEZOELECTRIC THIN FILM RESONATOR.	KOMURO, EIJU
10968976	7003875	150	10/21/2004	METHOD FOR MANUFACTURING PIEZO- RESONATOR	KOMURO, EIJU
10995365	7183879	150	11/24/2004	ELECTRIC FILTER, AND DUPLEXER USING THE SAME	KOMURO, EIJU
11490164	Not Issued	20	07/21/2006	Method of manufacturing thin- film electronic device	KOMURO, EIJU

Inventor Search Completed: No Records to Display.

	Last Name	First Name	
Search Another: Inventor	komuro	eiju	Search

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Time: 10:24:27

PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = SAITOU

First Name = HISATOSHI

1		[Q			
Application#					Inventor Name
<u>09472806</u>	6259187	150	12/28/1999	PIEZOELECTRIC BULK ACOUSTIC WAVE DEVICE	SAITOU, HISATOSHI
09558586	6198208			Thin film piezoelectric device	SAITOU, HISATOSHI
09842802	Not Issued	71	04/27/2001	Multilayer thin film and its fabrication process as well as electron device	SAITOU, HISATOSHI
09842805	<u>6709776</u>	150	04/27/2001	MULTILAYER THIN FILM AND ITS FABRICATION PROCESS AS WELL AS ELECTRON DEVICE	SAITOU, HISATOSHI
10650764	<u>6855996</u>	150	08/29/2003	ELECTRONIC DEVICE SUBSTRATE STRUCTURE AND ELECTRONIC DEVICE	SAITOU, HISATOSHI
10731157	6989723	150	12/10/2003	PIEZOELECTRIC RESONANT FILTER AND DUPLEXER	SAITOU, HISATOSHI
10811812	Not Issued	71	03/30/2004	Method of manufacturing a piezoelectric thin film resonator, manufacturing apparatus for a piezoelectric thin film resonator, piezoelectric thin film resonator, and electronic component	SAITOU, HISATOSHI
10814120	7109637	150	04/01/2004	THIN-FILM BULK ACOUSTIC OSCILLATOR AND METHOD OF MANUFACTURING SAME	SAITOU, HISATOSHI
10817907	Not Issued	93		SUBSTRATE FOR ELECTRONIC DEVICE, ELECTRONIC DEVICE AND METHODS OF MANUFACTURING SAME	SAITOU, HISATOSHI
10843568	7170370	150		FILTER DEVICE CAPABLE OF OBTAINING ATTENUATION	SAITOU, HISATOSHI

				CHARACTERISTIC OF SHARPNESS IN NARROW BAND WIDTH AND BRANCHING FILTER USING THE SAME	
10901382	Not Issued	41	,	•	SAITOU, HISATOSHI
10902525	Not Issued	93			SAITOU, HISATOSHI
10968976	7003875	150		METHOD FOR MANUFACTURING PIEZO- RESONATOR	SAITOU, HISATOSHI

Inventor Search Completed: No Records to Display.

	Last Name	First Name	
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Time: 10:25:04

Inventor Name Search Result

Your Search was:

Last Name = NOGUCHI First Name = TAKAO

	•				
Application#	Patent#	Status	Date Filed	Title	Inventor Name
06648878	4570453	150	09/10/1984	APPARATUS FOR CONTINUOUSLY COOLING HEATED METAL PLATE	NOGUCHI, TAKAO
07717028	5081858	150	06/18/1991	METHOD FOR FORMING A LUBRICANT COAT ON THE SURFACE OF A MATERIAL TO BE FORGED AND A FORGING DEVICE PROVIDED WITH A LUBRICANT COAT FORMING MEMBER	NOGUCHI, TAKAO
07728224	<u>5244587</u>	150	07/11/1991	FORGING LUBRICANT AND A METHOD FOR FORMING A LUBRICANT COAT ON THE SURFACE OF A LINEAR MATERIAL	NOGUCHI, TAKAO
08516356	5828080	150	08/17/1995	OXIDE THIN FILM, ELECTRONIC DEVICE SUBSTRATE AND ELECTRONIC DEVICE	NOGUCHI, TAKAO
08524809	5955213	150	09/07/1995	FERROELECTRIC THIN FILM, ELECTRIC DEVICE, AND METHOD FOR PREPARING FERROELECTRIC THIN FILM	NOGUCHI, TAKAO
08524904	5753934	150	,	MULTILAYER THIN FILM, SUBSTRATE FOR ELECTRONIC DEVICE, ELECTRONIC DEVICE, AND PREPARATION OF MULTILAYER OXIDE THIN FILM	NOGUCHI, TAKAO
08644829	5810923	150	05/10/1996	METHOD FOR FORMING OXIDE THIN FILM, AND THE TREATMENT OF SILICON SUBSTRATE	NOGUCHI, TAKAO
! '	li l	II I	1	II l	II I

08663741				MULTILAYER THIN FILM, SUBSTRATE FOR ELECTRONIC DEVICE, ELECTRONIC DEVICE, AND PREPARATION OF MULTILAYER OXIDE THIN FILM	NOGUCHI, TAKAO
08855444	5919515	150	05/13/1997	FERROELECTRIC THIN FILM, ELECTRIC DEVICE AND METHOD FOR PREPARING FERROELECTRIC THIN FILM	NOGUCHI, TAKAO
08883456	6121647	150	06/26/1997	FILM STRUCTURE, ELECTRONIC DEVICE, RECORDING MEDIUM, AND PROCESS OF PREPARING FERROELECTRIC THIN FILMS	NOGUCHI, TAKAO
08938009	Not Issued	161	09/12/1997	OXIDE THIN FILM, ELECTRONIC DEVICE SUBSTRATE, ELECTRONIC DEVICE, METHOD FOR FORMING OXIDE THIN FILM, AND TREATMENT OF SILICON SUBSTRATE	NOGUCHI, TAKAO
09044227	6096434	150	03/19/1998	FILM STRUCTURE ELECTRONIC DEVICE, RECORDING MEDIUM, AND METHOD FOR FORMING CONDUCTIVE OXIDE THIN FILMS	NOGUCHI, TAKAO
09102568	6045626	150	14	SUBSTRATE STRUCTURES FOR ELECTRONIC DEVICES	NOGUCHI, TAKAO
09453505	6387712	150	12/03/1999	PROCESS FOR PREPARING FERROELECTRIC THIN FILMS	NOGUCHI, TAKAO
09558586	6198208	150	04/26/2000	Thin film piezoelectric device	NOGUCHI, TAKAO
09842802	Not Issued	71	04/27/2001	Multilayer thin film and its fabrication process as well as electron device	NOGUCHI, TAKAO
09842805	6709776	150		MULTILAYER THIN FILM AND ITS FABRICATION PROCESS AS WELL AS ELECTRON DEVICE	NOGUCHI, TAKAO
10650764	6855996	150		ELECTRONIC DEVICE SUBSTRATE STRUCTURE AND ELECTRONIC DEVICE	NOGUCHI, TAKAO

10501155	7077		7	\	
10731157	6989723	150	12/10/2003	PIEZOELECTRIC RESONANT FILTER AND DUPLEXER	NOGUCHI, TAKAO
10786776	7042090	150	02/24/2004	ELECTRONIC DEVICE AND METHOD OF FABRICATING THE SAME	NOGUCHI, TAKAO
	Not Issued	71		Method of manufacturing a piezoelectric thin film resonator, manufacturing apparatus for a piezoelectric thin film resonator, piezoelectric thin film resonator, and electronic component	NOGUCHI, TAKAO
10817907	Not Issued	93	04/06/2004	SUBSTRATE FOR ELECTRONIC DEVICE, ELECTRONIC DEVICE AND METHODS OF MANUFACTURING SAME	NOGUCHI, TAKAO
11028891	Not Issued	71	01/03/2005	Component for fabricating an electronic device and method of fabricating an electronic device	NOGUCHI, TAKAO
11028992	7173361	150	01/03/2005	FILM BULK ACOUSTIC WAVE RESONATOR	NOGUCHI, TAKAO
11061883	7075214	150	02/22/2005	PIEZOELECTRIC RESONATOR AND ELECTRONIC COMPONENT PROVIDED THEREWITH	NOGUCHI, TAKAO
11069723	7105880	150	02/28/2005	ELECTRONIC DEVICE AND METHOD OF FABRICATING THE SAME	NOGUCHI, TAKAO
11078565	Not Issued	90		THIN-FILM PIEZOELECTRIC ELEMENT AND METHOD OF MAKING SAME	NOGUCHI, TAKAO
11079211	7148604	150	03/15/2005	PIEZOELECTRIC RESONATOR AND ELECTRONIC COMPONENT PROVIDED THEREWITH	NOGUCHI, TAKAO
11360394	Not Issued	30		Electronic device and method of making same	NOGUCHI, TAKAO

Inventor Search Completed: No Records to Display.

Search Another: Inventor	Last Name	First Name	
	noguchi	takao	Search

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Day: Thursday Date: 3/15/2007

Time: 10:25:39

Inventor Name Search Result

Your Search was:

Last Name = IMURA First Name = MASAAKI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
10380985	7187254	150	03/20/2003	FILM BULK ACOUSTIC RESONATOR FILTERS WITH A COPLANAR WAVEGUIDE	IMURA, MASAAKI
10670234	6977563	150	09/26/2003	THIN-FILM PIEZOELECTRIC RESONATOR AND METHOD FOR FABRICATING THE SAME	IMURA, MASAAKI
10718799	7199504	150	11/24/2003	FILM BULK ACOUSTIC RESONATOR FILTER	IMURA, MASAAKI
10811812	Not Issued	71	03/30/2004	Method of manufacturing a piezoelectric thin film resonator, manufacturing apparatus for a piezoelectric thin film resonator, piezoelectric thin film resonator, and electronic component	IMURA, MASAAKI
11568823	Not . Issued	19	01/01/0001	RARE EARTH SINTERED MAGNET, RAW MATERIAL ALLOY POWDER FOR RARE EARTH SINTERED MAGNET, AND PROCESS FOR PRODUCING RARE EARTH SINTERED MAGNET	IMURA, MASAAKI

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	imura	masaaki	Search

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